

Printer Friendly

10/709,980 METHOD OF FORMING A THIN FILM TRANSISTOR BY UTILIZING A LASER

CRYSTALLIZATION PROCESS

Image File Wrapper

This application is officially maintained in electronic form. To View: Click the desired Document Description. To Download and Print: Check the desired document(s) and click StartDownload.

Mail Room Date	Document Description	Page Count
06-17-2005	Non-Final Rejection	5
06-17-2005	List of references cited by examiner	1
06-17-2005	Search information including classification, databases and other search related notes	1
06-17-2005	Bibliographic Data Sheet	1
06-17-2005	Index of Claims	1
06-14-2005	Examiner's search strategy and results	10
06-29-2004	Foreign Priority Papers Filed	62
06-10-2004	Status Letter Mailed to Applicant	2
06-10-2004	Drawings	14
06-10-2004	Abstract	1
06-10-2004	Claims	5
06-10-2004	Specification	26
06-10-2004	Transmittal letter	3
06-10-2004	Oath or Declaration filed	3
06-10-2004	Fee Worksheet (PTO-875)	2
06-10-2004	Application Data Sheet	2
06-10-2004	Power of Attorney (may include Associate POA)	1

[Close Window](#)

PATENT
Docket No TOPP0016USA

COMBINED DECLARATION AND POWER OF ATTORNEY

As a below named inventor, I hereby declare that:

I believe I am the sole (if only one name appears below), or joint (if more than one name appears), original and first inventor of the subject matter which is claimed and for which a patent is sought on the invention entitled:

"METHOD OF FORMING A THIN FILM TRANSISTOR BY UTILIZING A LASER CRYSTALLIZATION PROCESS"

The specification for the above entitled invention is filed herewith.

The specification for the above entitled invention was filed previously with application serial number: _____ Filing Date: _____

I hereby state that I have reviewed and understand the contents of the above identified specification, including the claims, as amended by any amendment referred to above.

I acknowledge the duty to disclose information which is material to the patentability of the invention disclosed in this application in accordance with Title 37, Code of Federal Regulations, Section 1.56 (a). I further acknowledge the duty in any continuation-in-part application to disclose to the Patent and Trademark Office all information known to be material to the patentability of the invention disclosed in this application, as defined in 1.56, which became available to me between the filing date of the prior application and the filing date of this application.

PRIORITY CLAIM

There is no claim of priority

Claim of priority is based on the following:

Filing No. in Taiwan, R.O.C.: 092116013

Filing date in Taiwan, R.O.C.: 2003/6/12

POWER OF ATTORNEY

As a named inventor, I hereby appoint the following attorneys to prosecute this application and to transact all related business in the Patent and Trademark Office:

Winston Hsu

Registration# 41,526

P.O. Box 506,
Merrifield, Virginia 22116,
U.S.A

E-mail : winstonhsu@naipo.com.tw
TEL: +886-2-89237350 *100

DECLARATION

I hereby declare that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment or both under Section 1001 of Title 18 of the United States Code and that such willful false statements may jeopardize the validity of the application or any patent issued hereon.

(請聲明人務必簽署日期)

Date: 2004.6.7Ching-Wei Lin

Printed Name: Ching-Wei Lin
Post Office Address:
and Residence No. 212, Lung-Shan St., Tou-Yuan City, Tao-Yuan
Hsien, Taiwan, R.O.C.
Citizen of: R.O.C.